

Tailoring Electrical Contact Resistivity at Metal-Thermoelectric Interfaces Using a Molecular Nanolayer

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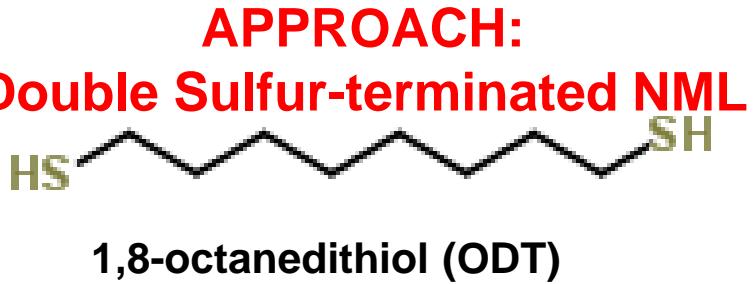


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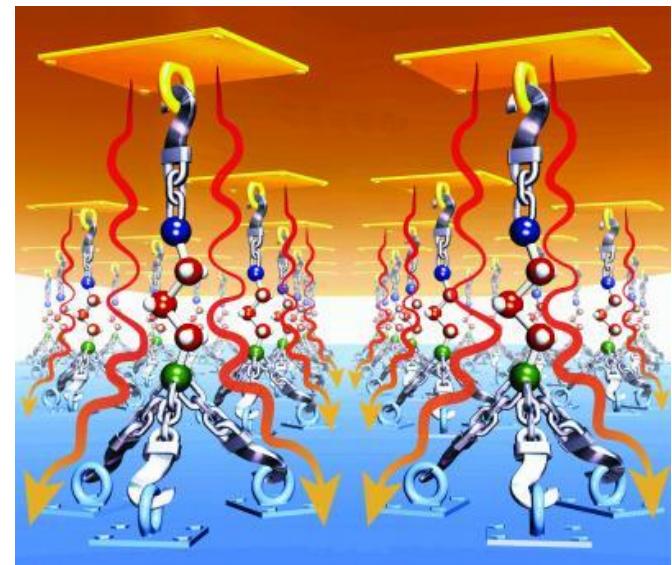
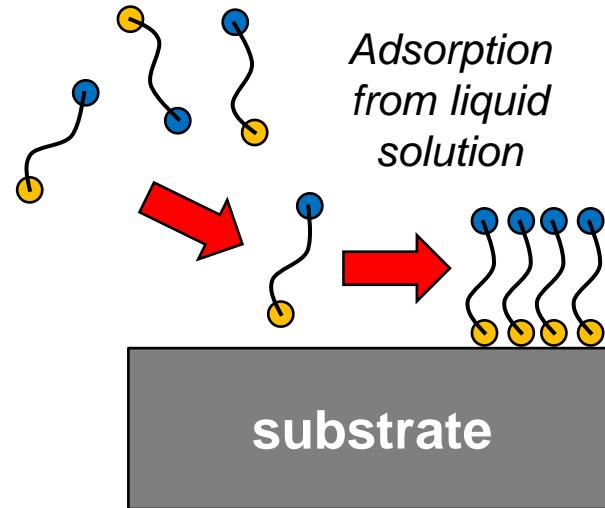
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Nanomolecular monolayers (NML)

- Self assembly
- Diffusion barriers in Cu- based systems^[1]
[1] P. G Ganeshan et al., *Appl. Phys. Lett.*, (2004)
- Improve thermal conductivity^[2] and mechanical strength^[3] of Cu-SiO₂ interfaces
[2] P. O'Brien et al., *Nat Mat.* (2012)
[3] D.D. Gandhi et al., *Nature* (2007)
- Organosilanes found to improve Au/Ni-Bi₂Te₃ interface resistivity^[4]
[4] S.P. Feng et al., *PCCP* (2013)



S-Metal bonds known to form^[1,2,3]
S-Bi, S-Te bonds known to form as well^[5]
[5] R.J. Mehta et al., *Nat. Mat* (2012)



NML-Functionalized Bi₂Te₃

GOAL:

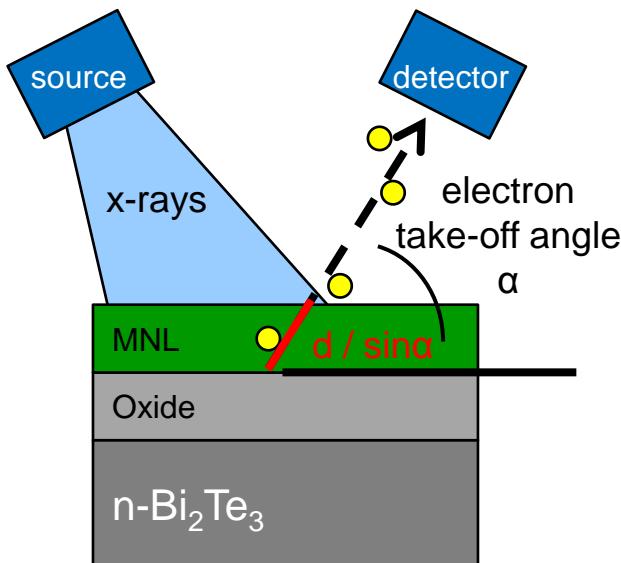
Achieve a single edge-standing layer of ODT

FUNCTIONALIZATION PROCEDURE

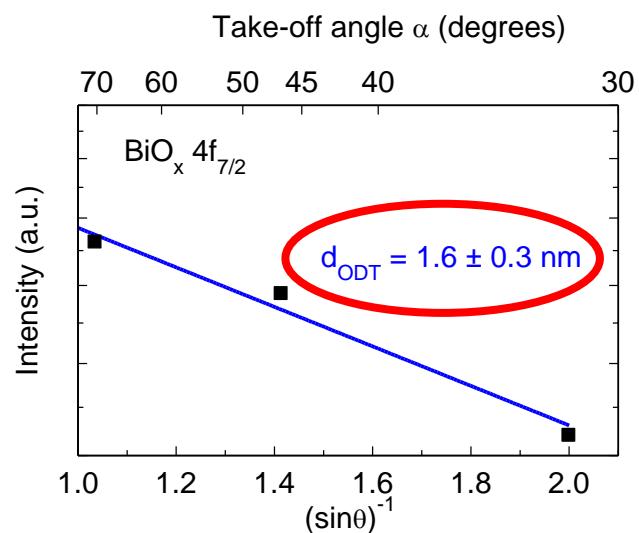
- 5 mM ODT in ethanol prepared
- n-Bi₂Te₃ samples polished with 1200 grit SiC
- Samples immersed in solution for 60 min
 - Low humidity glovebox
- Sonicate in ethanol to remove physisorbed species



[1] Jun et al., Langmuir (2006)

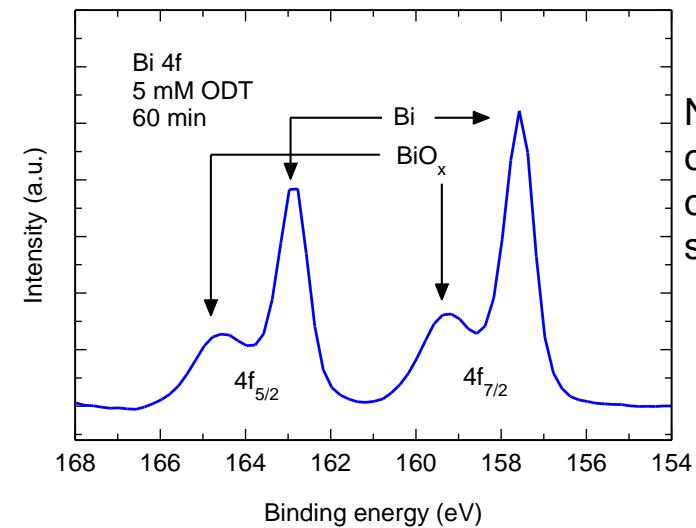


Variable take-off angle XPS measures MONOLAYER of ODT

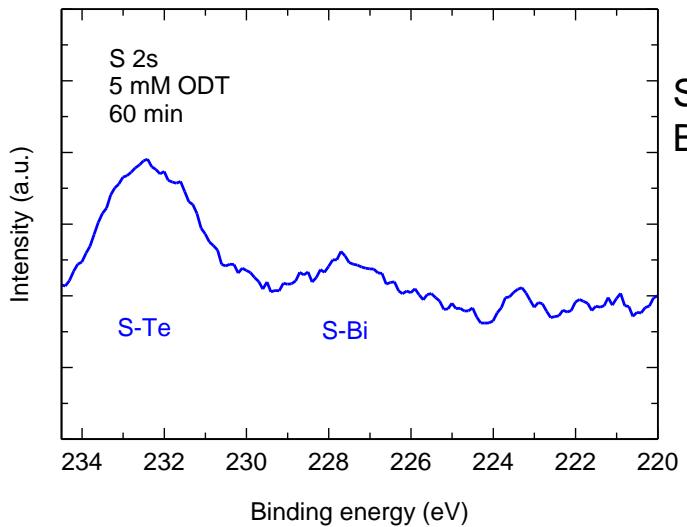


$$\ln I = -\frac{1}{\sin \alpha} \frac{d_{\text{MNL}}}{\lambda_{\text{MNL}}} + k$$

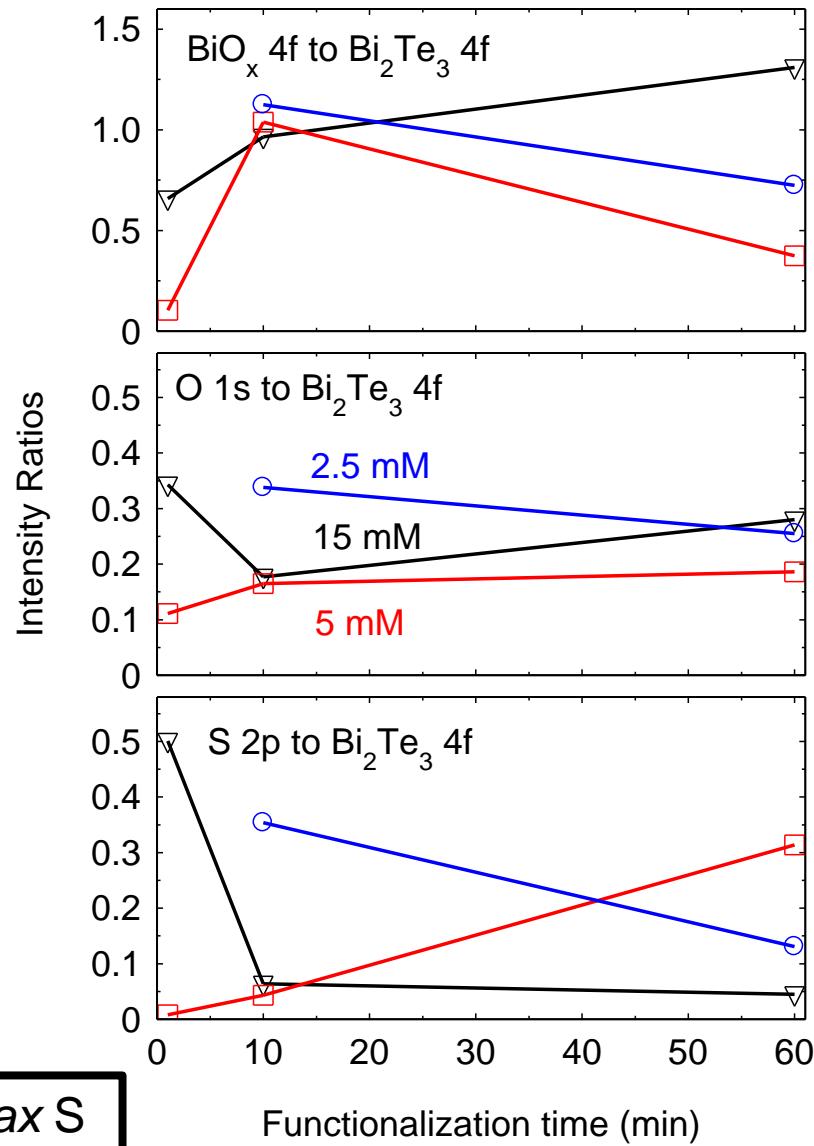
NML Characterization on Bi_2Te_3 Surfaces



Nanoscale
oxide formation
on Bi_2Te_3
surface.



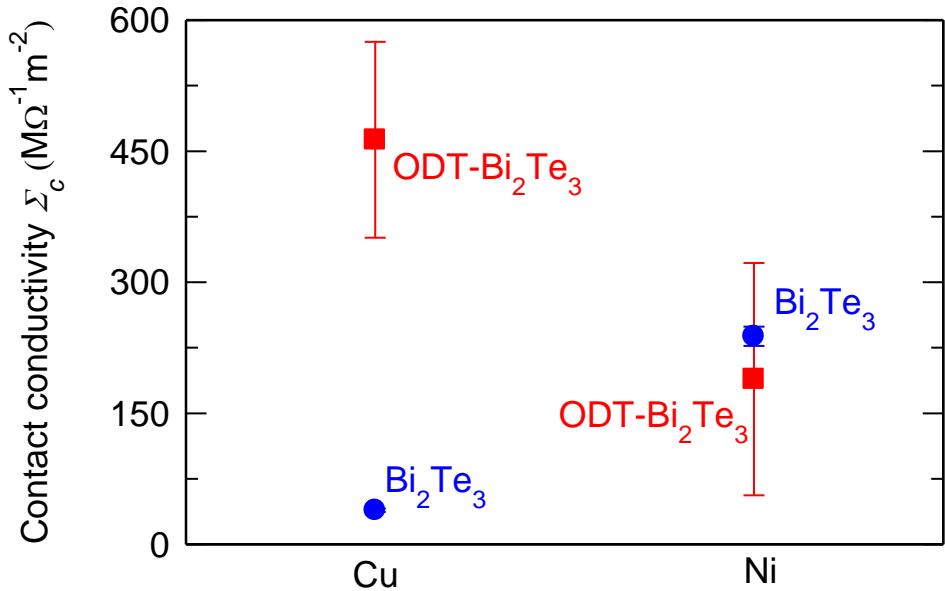
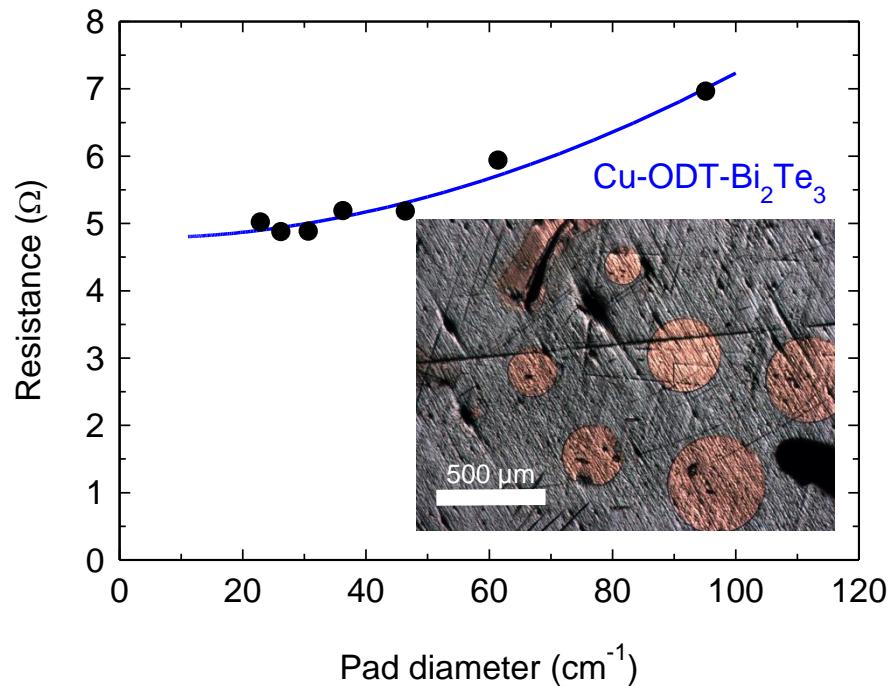
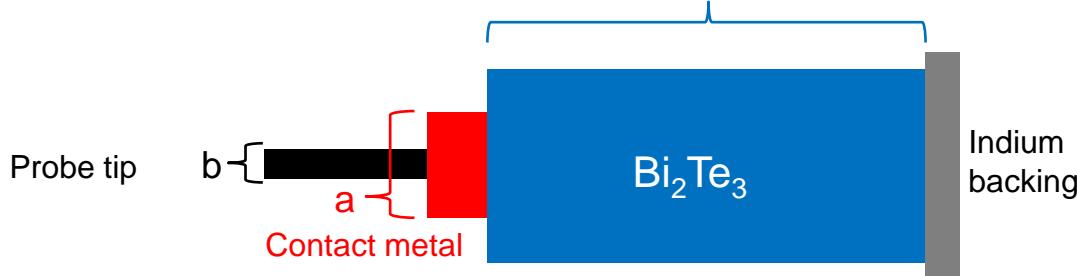
Sulfur bonding with
 Bi_2Te_3 surface



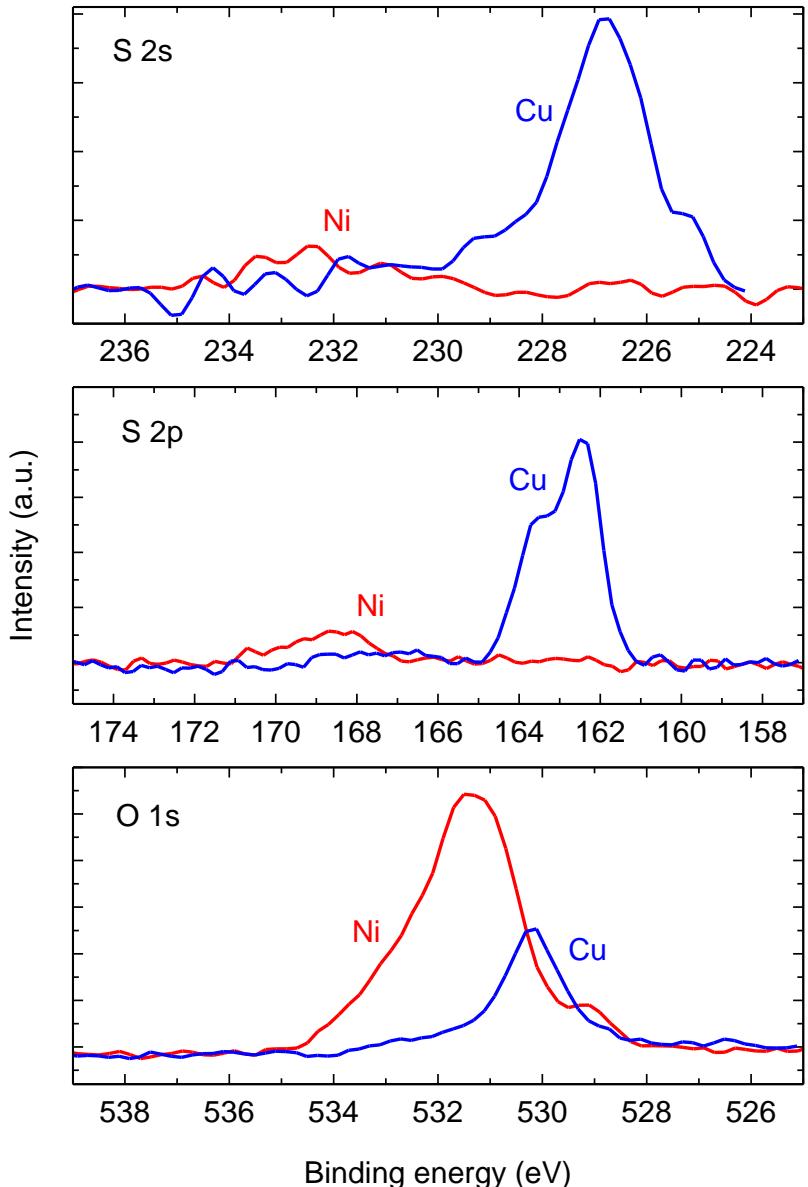
Min BiO_x , O & Max S
for 5 mM, 60 min

Contact conductivity, Σ_c via Cox & Strack method

$$R_t = \left[\frac{R_{sm}}{2\pi} \ln \frac{a}{b} - \frac{R_{sm}}{4\pi} \left(1 - \frac{b^2}{a^2} \right) \right] + \left[\frac{4R_c}{\pi} \frac{1}{a^2} + \frac{\rho}{\pi a} \tan^{-1} \left(\frac{4t}{a} \right) \right] + R_o$$

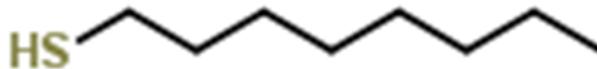


Bonding characteristics of S-Cu & S-Ni



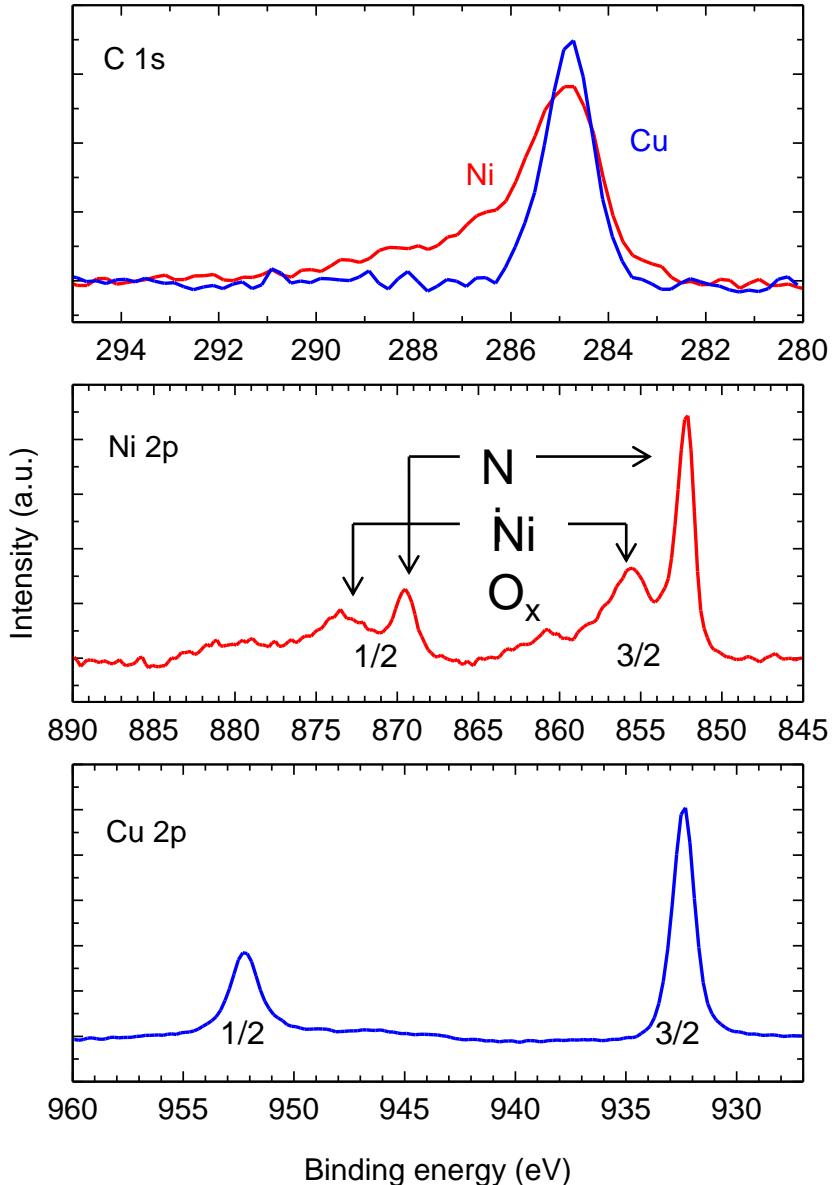
EXPERIMENT:

- Cu, Ni pellets immersed in 5 mM solution of *1-Octanethiol* for 1 hour, rinsed & sonicated in ethanol
- XPS characterization immediately afterward



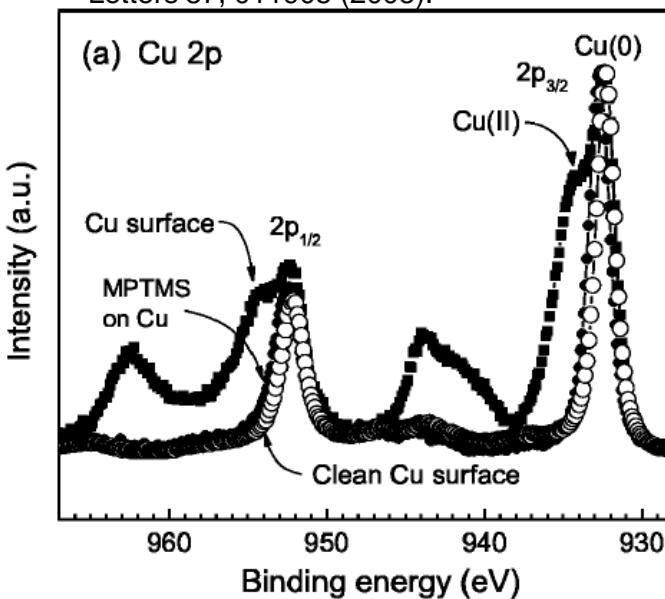
- **Stronger S signal on Cu vs Ni**
 - S readily bonds with Cu
- **O scavenged by S in Cu system**

Bonding characteristics of S-Cu & S-Ni

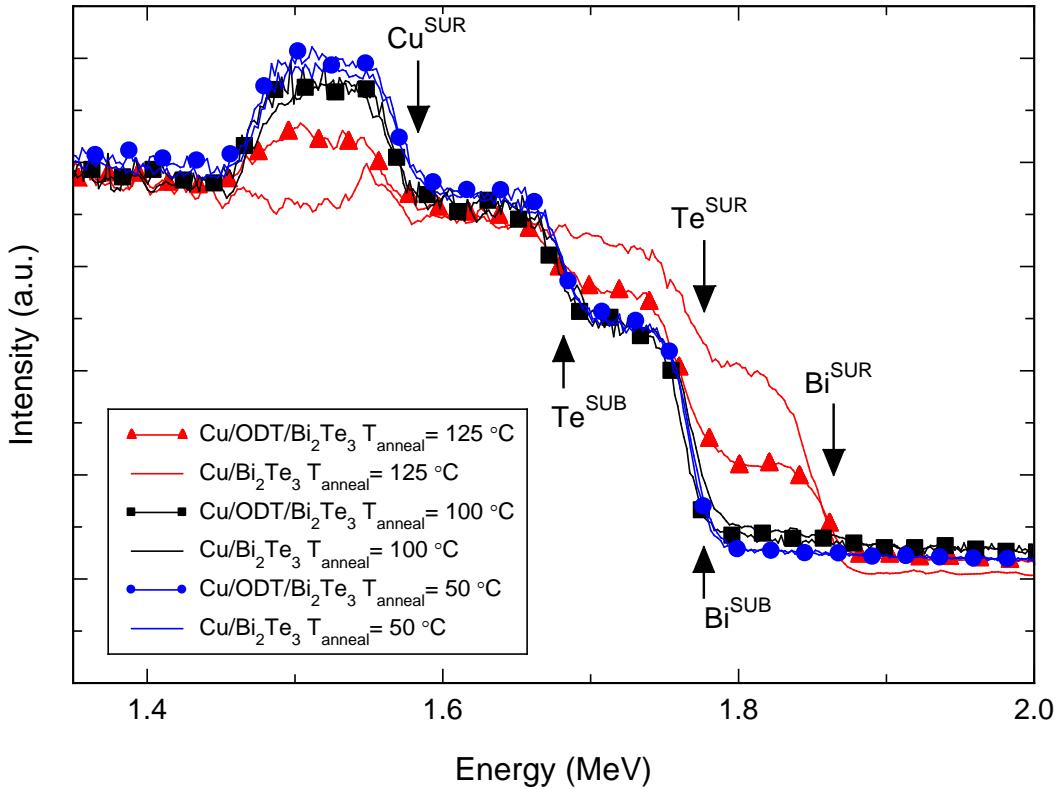


- Broader C 1s signal on Ni
 - Presence of C bonds other than -[CH₂]- groups
 - Ni₃C, CO-Ni, CO, CO₂
- NiO_x band clearly present in Ni 2p
- Cu 2p band shows only Cu⁰ state.
No oxide detected.

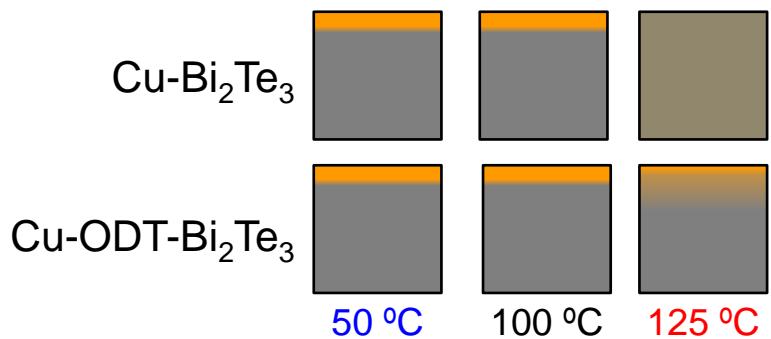
P.G. Ganesan, et al., Applied Physics Letters 87, 011905 (2005).



Diffusion characteristics of Cu-ODT-Bi₂Te₃ via RBS

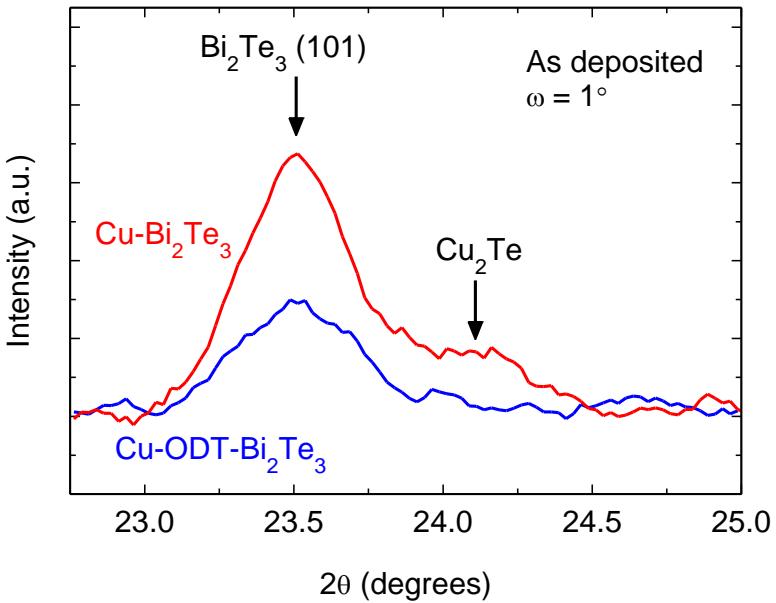


- Very little interdiffusion upon annealing at 50 °C and 100 °C
- Almost no Cu on surface without ODT after anneal at 125 °C
- Considerable amount of Cu on surface with ODT after 125 °C anneal
 - Some Bi & Te are at surface for system with ODT

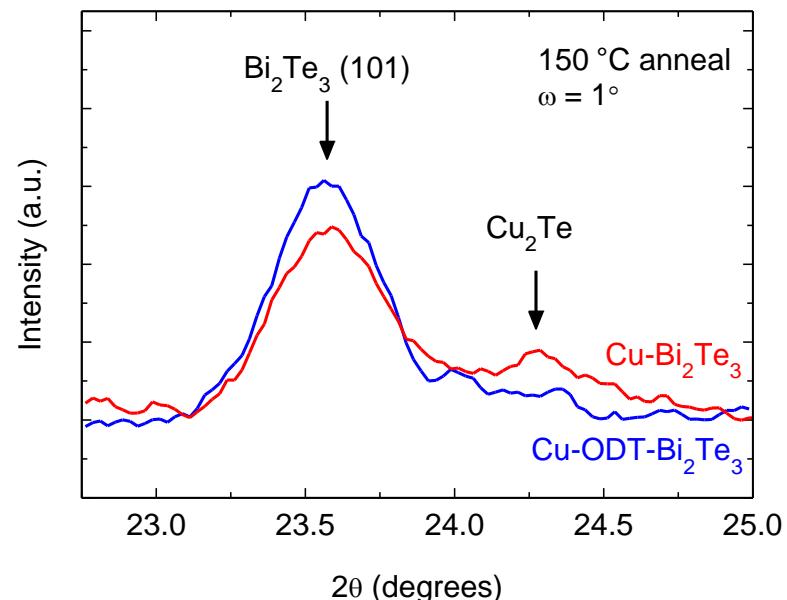
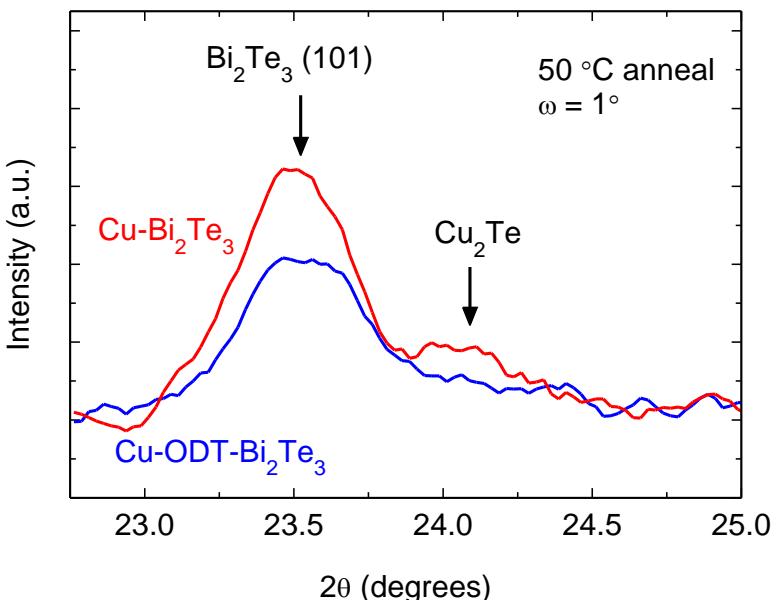


ODT is inhibiting Cu diffusion upon annealing.

Grazing Incidence XRD (GID)



- GID reveals Cu₂Te phases not detected via standard $\theta - 2\theta$ diffraction.
- Cu₂Te signal suppressed when ODT is present at interface upon annealing.



Concluding remarks

- ODT able to self-assemble on Bi_2Te_3 surface
- Interfacial chemistry impacts electric contact conductivity
 - Σ_c 10 times higher when ODT at Cu- Bi_2Te_3 interface
 - 20% decrease in Σ_c when ODT at Ni- Bi_2Te_3 interface
 - Strong Cu-S bonding in comparison to Ni-S bonding
- Σ_c enhancement for Cu- Bi_2Te_3 system due to interfacial preservation
 - ODT found to be diffusion barrier
 - Cu_2Te formation suppressed
- Careful selection of NML with interfacial system critical to achieve desired properties

Acknowledgements

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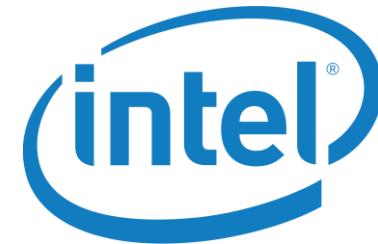
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